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J. Wilson 5/24/01



CA

503.30414C14

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

15/10

Applicant(s): KATO, et al.
Serial No.: 09/461,432
Filed: December 16, 1999
For: VACUUM PROCESSING APPARATUS AND OPERATING METHOD THEREFOR
Group: 3749
Examiner: S. Gravini
Allowed: December 7, 2000
Batch No.: W11

Match and Return

FURTHER AMENDMENT UNDER 37 CFR 1.312

Assistant Commissioner for Patents
Box Issue Fee
Washington, D.C. 20231

March 7, 2001

Sir:

Further amending the claims as proposed to be amended in the Amendment Under 37 CFR 1.312 submitted January 18, 2001, and concurrently with payment of the Issue Fee responsive to the Notice of Allowance mailed December 7, 2000, please further amend the above-identified application as follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

1. (Twice Amended) A method of using a conveyor system for processing substrates in plural vacuum processing chamber installation portions, the conveyor system including:
an atmospheric loader, having a location for

SUB E1
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